

Notice of References Cited			Application/Control No.	Applicant(s)/Patent Under Reexamination	
			10/810,106	YANG ET AL.	
Examiner		BRET CHEN	Art Unit	1792	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	C	US-6,863,019	03-2005	Shamoulian et al.	118/723R
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	L	US-			
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NON-PATENT DOCUMENTS

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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a))
 Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.